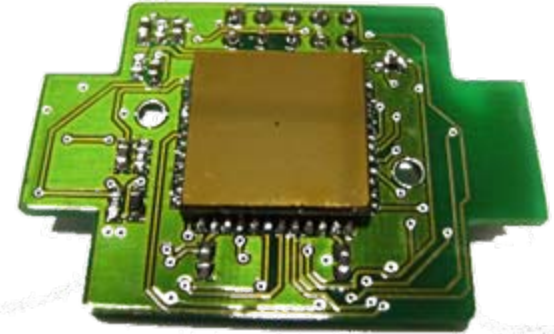




# Miniature Digital Sun Sensor for Application in Nano- and Picosatellites

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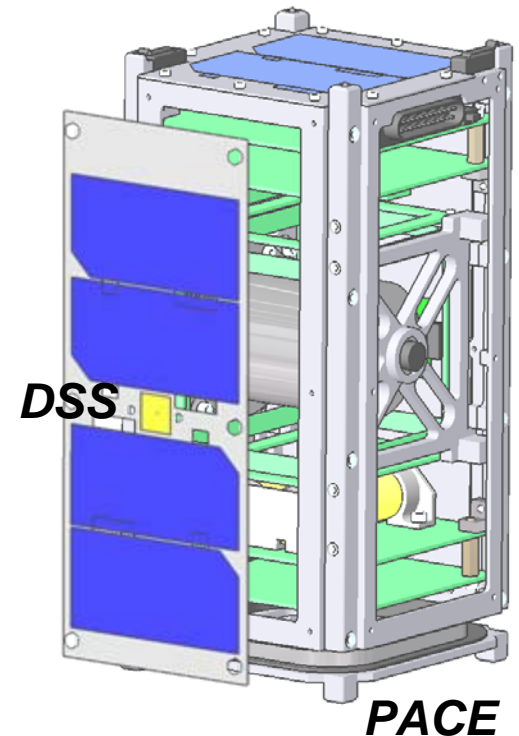


# Research Objectives

- Development of a precise digital sun sensor
- Suitable for CubeSats and Nanosatellites
- Realize large field of view
- Accuracy in the order of 1 deg

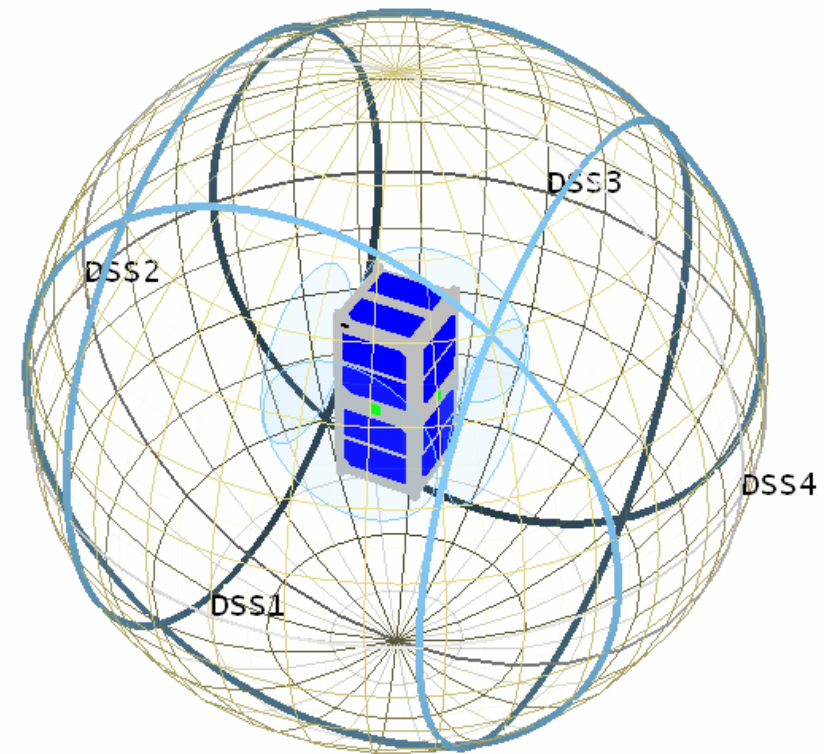
# Motivation and Purpose

- To be used on PACE (2kg) and LEAP (30kg) satellites, both being developed at National Cheng Kung University.



# Specification of Digital Sun Sensor

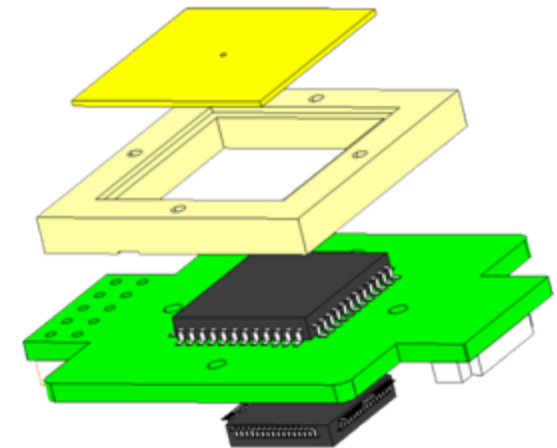
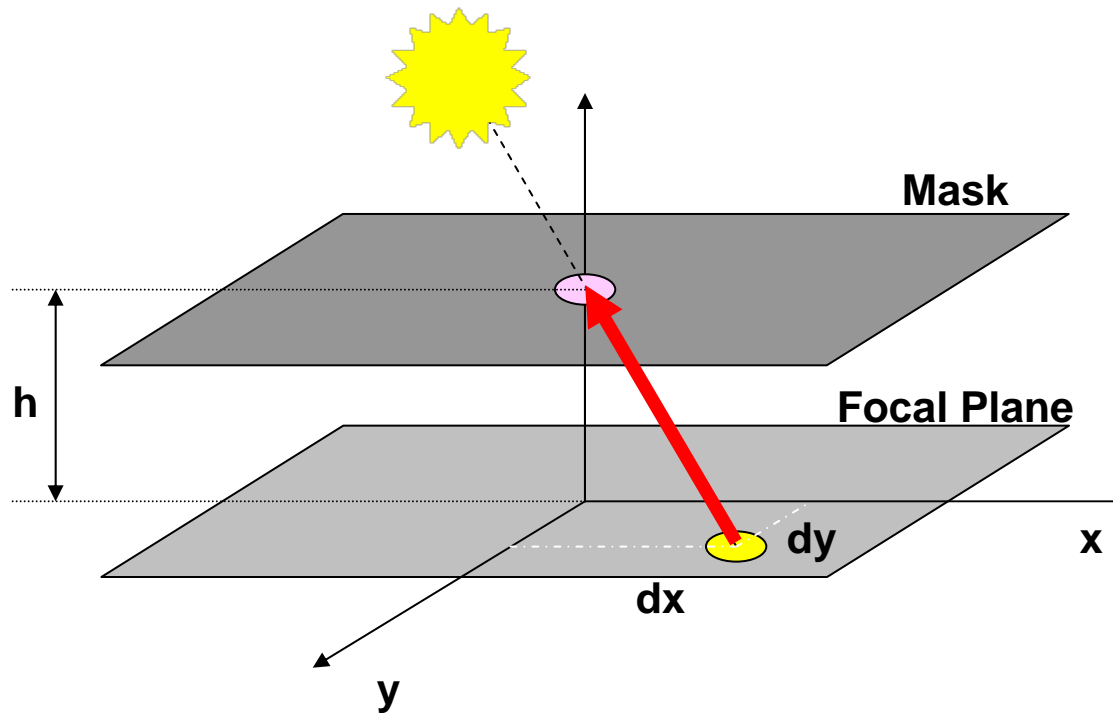
- 120° x 120° Field of View
- 1 Hz update rate
- <math><0.5^\circ</math> resolution (TBC)
- <math><1^\circ</math> accuracy (TBC)
- 20 grams total mass
- 3.3 Volt supply, max. 0.2W
- 42mm x 29mm x 5mm



***Coverage of 4 DSS (one per side)***

# Measurement Principle

- A pinhole mask is placed in front of an image sensor.
- The sun light will form a sun spot on the focal plane.
- Determination of the spot center yields a sun pointing vector.



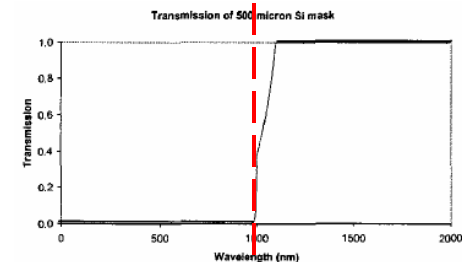
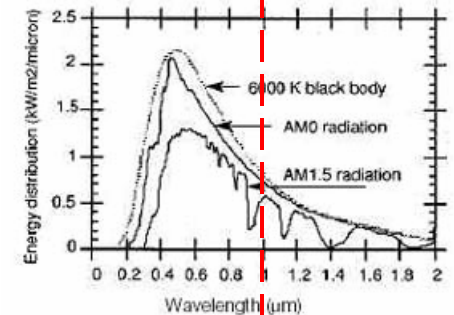
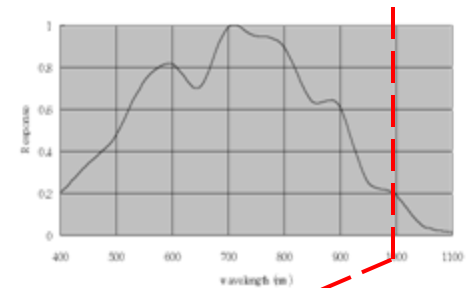
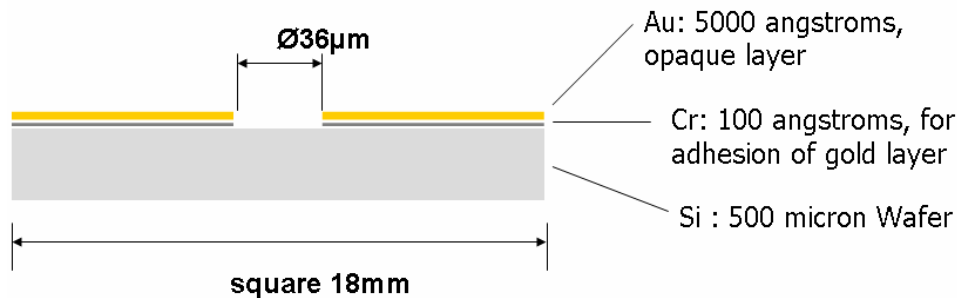
# Hardware (1/2)

## • Image Sensor

- CMOS B/W image sensor
- 512 x 512 pixels (8 bit), 12 $\mu$ m pixel size
- On-chip in-pixel analog frame-buffer (200 ms)
- Clock-less and X-Y addressed image readout
- On-chip 8-bit A/ D converter

## • Mask

- MEMS technology, Si wafer

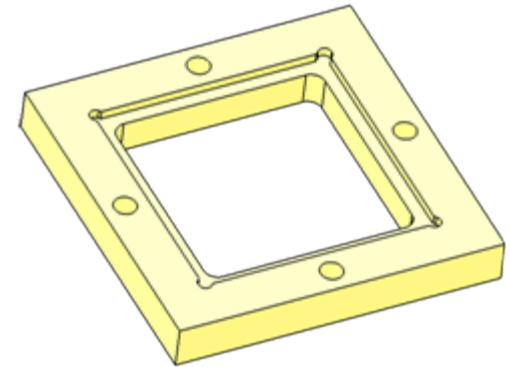




# Hardware (2/2)

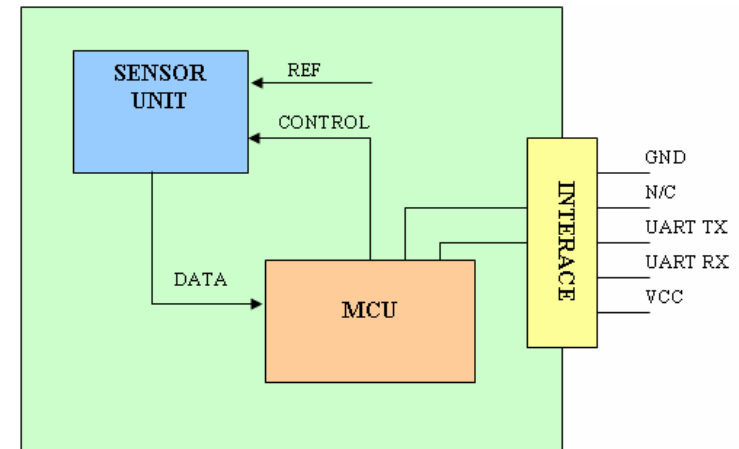
- **Mask Spacer**

- Placing the mask at a certain distance in front of the image sensor has impact on the FOV.
- Made of Teflon to achieve thermal decoupling from the panel it is mounted to.



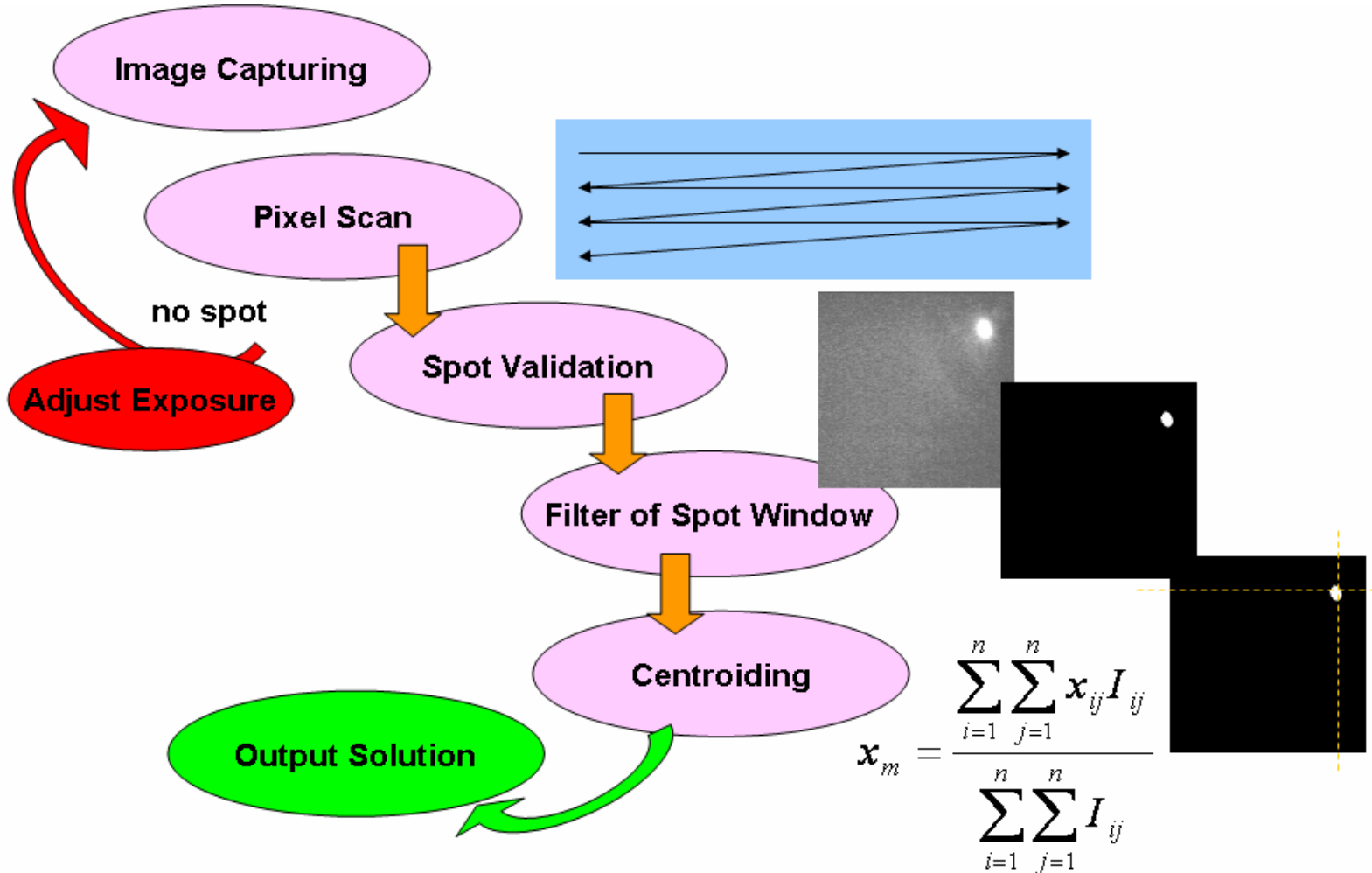
- **Microcontroller**

- C8051F123 MCU
- Provides 9600/38400 bps UART I/F
- Controls Sensor and runs filter and detection algorithms





# Software

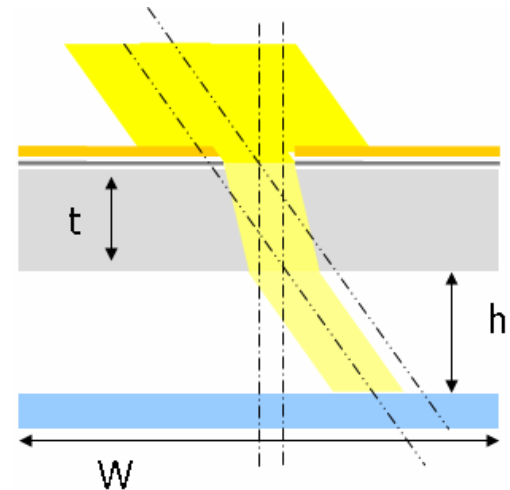


# Performance Assessment (1/2)

- **Resolution**

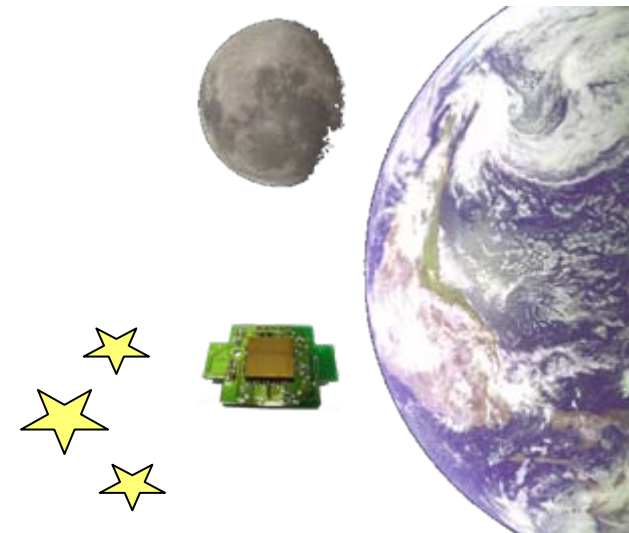
With a distance of  $h = 1500\mu\text{m}$ :

- FOV =  $\pm 63.3^\circ$
- Resolution @ nadir =  $0.46^\circ$
- Resolution @  $45^\circ$  =  $0.23^\circ$
- Resolution @  $60^\circ$  =  $0.16^\circ$



- **Disturbances and Noise**

- Si wafer filters out IR sources and most of the noise
- Thresholding and spot detection cancels out the effects of Albedo and Moon reflection

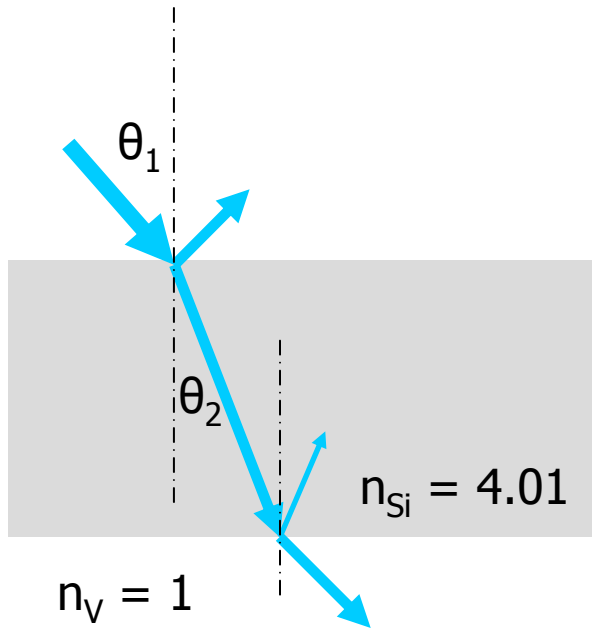




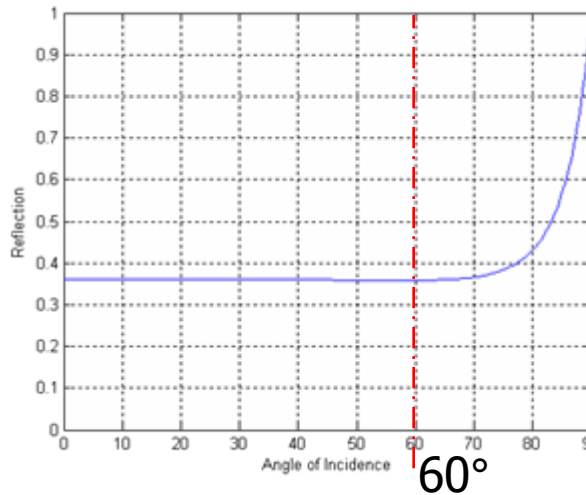


# Performance Assessment (2/2)

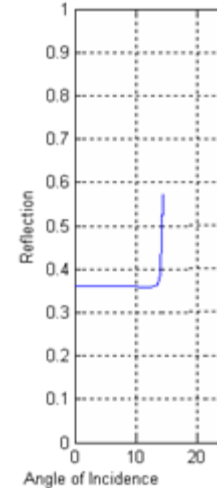
- Reflection and Refraction in the Mask



Reflection Vacuum-Si

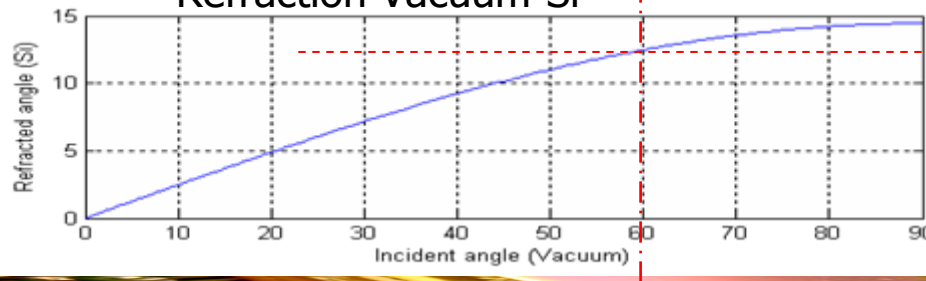


Reflection Si-Vacuum



$R(12.5^\circ) = 0.36$

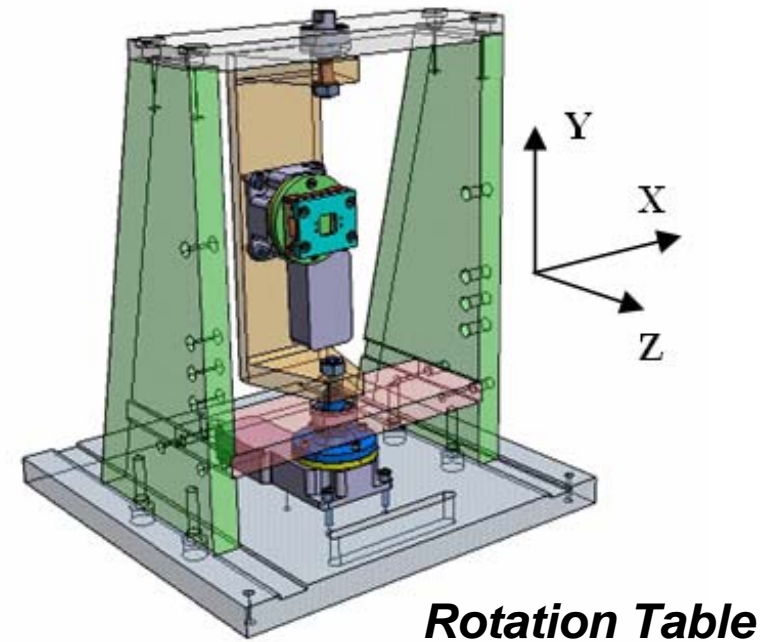
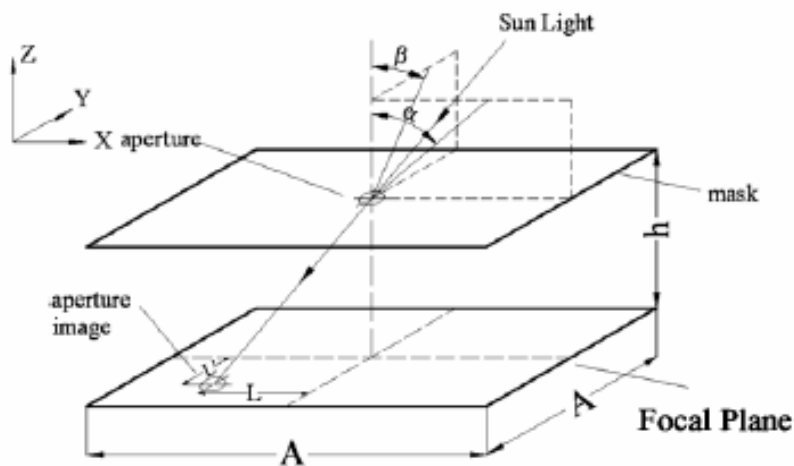
Refraction Vacuum-Si



$12.5^\circ$

# Calibration Procedure (Planned)

- Rotation table and sun simulator aperture for determination of:
  - Field of View
  - Parameters  $h, x_0, y_0$
  - Accuracy over entire FOV



$$\begin{bmatrix} x_p \\ y_p \end{bmatrix} = \begin{bmatrix} -h \cdot \cos \varphi \tan \theta + x_0 \\ h \cdot \sin \varphi \tan \theta + y_0 \end{bmatrix}$$



Thank you for your attention!  
...Questions ?

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more at:

[www.nspo.org.tw/ASC2008](http://www.nspo.org.tw/ASC2008)





# Backup Slides



# Functional Testing of Prototype

